



CiS Institut für Mikrosensorik gGmbH

D - 99097 Erfurt, Konrad-Zuse-Straße 14

Name of the institution: CiS Institut für Mikrosensorik gGmbH

Konrad-Zuse-Straße 14

D-99099 Erfurt

and contact person: Ralf Röder, Product Manager SD&FD

Tel.: +49 361 / 6631 461

email: roeder@cismst.de

Names of group members and fraction of their time devoted to this activity:

Mr. H. Übensee, Dr. Sensor R&D

Mr. D. Stolze Manager Wafer Fabrication

Time for this activities depends on R&D-project budgets.

Current activities: R&D Project in collaboration with University of Hamburg:

- i) Radiation hardening by using DOFZ
- ii) Test wafer processing: CZ high ohmic bulk
- iii) Test wafer processing: epitactical layer

Wafer fabrication: ATLAS WEDGE, ATLAS PIXEL, ALICE

Prototyping: CMS PIXEL

Field of interest within this collaboration:

1. Detector processing:
Improving technology for radiation hard detectors;
oxygenated wafers
perhaps new materials
2. New detector structures & detector design

Available resources (Instrumentation, irradiation facilities etc.):

1. Wafer processing line: 4"; double side processing capability
2. double side wafer probing capability
3. Device and Technology modelling & simulation
4. silicon, ceramic and glass slicing
5. bonding, bumping, glueing
6. housing
 - ceramic or glass hybrid,
 - silicon and epoxy [also partial/selective]

For more information see also: <http://www.cismst.de> or <http://www.cismst.de/deutsch/frameset.html>.